

Application No.: 10/688,810  
Amendment dated July 5, 2005  
Reply to Office Action of April 5, 2005

**Amendments to the Specification:**

Please replace paragraph [1044] with the following amended paragraph:

[1044] The depicted shaped beam system includes an evacuated chamber 410 having a ~~liquid metal~~ an ion source 414, such as a liquid metal ion source of a plasma microbeam ion source, and a focusing column 417, which includes an optical system such as is shown in the block diagram of Figure 5 for defining a desired shaped ion beam 418 and focusing it onto a target work piece 422. (It should be recognized that the term "focus" is used broadly, refers generally to the re-directioning of source ions into a beam directed to the target work piece, and covers shaped beams that are technically defocused with respect to a first-order focal plane.) Focusing column 417 uses a two-lens ion focusing structure for generating an angular apertured shaped beam. Skilled persons will understand that the lenses and other "optical" elements used with focused ion beams use electrostatic or magnetic fields to control ions in the beam, and that the optical elements are controlling a stream of ions. Also, the designs may include only one or up to several lenses. Moreover, while the principles of the angular apertured approach are discussed using this FIB system, they apply equally to other charged particle systems (such as e-beam systems) as long as suitable optical components for such other systems are used.